

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Prior Application: N. HASEGAWA et al
Serial No. 08/904,754
Filed: August 1, 1997

Group Art Unit: 1752
Examiner: S. Rosasco
For: PHOTOMASK AND PATTERN FORMING METHOD
EMPLOYING THE SAME



INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner of Patents
Washington, D.C. 20231

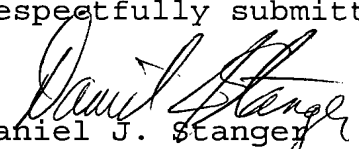
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D.C.
1-27-99

Sir:

In accordance with the duty of disclosure, the applicants inform the Examiner of the documents cited during prosecution of the parent application, USSN 08/904,754.

The applicants request the Examiner to initial and return a copy of the attached PTO-1449 form as an indication that the references have been considered.

Respectfully submitted,


Daniel J. Stanger
Registration No. 32,846
Attorney for Applicant(s)

FAY, SHARPE, BEALL,
FAGAN, MINNICH & MCKEE
104 East Hume Avenue
Alexandria, Virginia 22301
(703) 684-1120
Date: November 10, 1998